

Title (en)
CONVEYOR SYSTEMS AND METHODS

Title (de)
FÖRDERSYSTEME UND -VERFAHREN

Title (fr)
SYSTÈMES ET PROCÉDÉS POUR TRANSPORTEUR

Publication
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Application
EP 17899125 A 20170831

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Abstract (en)
[origin: WO2018160218A1] Embodiments of the invention provide systems and methods for monitoring and removing contaminants from a conveyor surface based upon predicted frictional engagement qualities detected on a conveyor surface. In some examples, the methods may include monitoring the conveyor surface with at least one sensor configured to sense a condition on the conveyor surface. The sensor may detect the presence of a contaminant, and communicate the location of the detected contaminant to a processor. A treatment cycle may then be initiated to remove or displace the contaminant from the conveyor surface after the presence of a contaminant has been detected.

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Citation (search report)
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• [X] US 6321586 B1 20011127 - WOJTOWICZ EDWARD A [US], et al
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Designated contracting state (EPC)
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